- [8] A. Fridman, *Plasma Chemistry*, 1st ed., Cambridge, England: Cambridge University Press, 2008.
- [9] S. Lyon, "Materials selection for corrosion control," *International Materials Reviews*, vol. 40, pp. 135-136, Jul. 2013.
- [10] Y. Hu, O. K. Tan, J. S. Pan, H. Huang, and W. Cao, "The effects of annealing temperature on the sensing properties of low temperature nano-sized SrTiO<sub>3</sub> oxygen gas sensor," *Sensors and Actuators B: Chemical*, vol. 108, pp. 244-249, Jul. 2005.
- [11] B. Huang, G. He, and H. Yang, "Effects of annealing on excitonic properties of sputtered ZnO films at room temperature," *Journal of Optoelectronics and Advanced Materials*, vol. 12, pp. 2369-2372, 2010.
- [12] H. Y. Liu, G. S. Tang, F. Zeng, and F. Pan, "Influence of sputtering parameters on structures and residual stress of Aln films deposited by DC reactive magnetron sputtering at room temperature," *Journal of Crystal Growth*, vol. 363, pp. 80-85, Jan. 2013.
- [13] X. Ding and Y. Lai, "Electrical and optical properties of zinc oxide thin films deposited by magnetron sputtering," *ECS Transactions*, vol. 34, pp. 577-582, Mar. 2011.
- [14] J. J. Kim, J. H. Lee, J. Y. Lee, D. J. Lee, B. R. Jang, and H. S. Kim, "Characteristics of ZnO films deposited on plastic substrate at various RF sputtering powers," *Journal of Korean Physical Society*, vol. 55, pp. 1910-1914, Nov. 2009.
- [15] J. H. Park, J. M. Shin, S. Cha, J. W. Park, S. Jeong, H. K. Pak, and C. Cho, "Deposition-temperature effects on AZO thin films prepared by RF magnetron sputtering and their physical properties," *Journal of the Korean Physical Society*, vol. 49, pp. S584-S588, Dec. 2006.
- [16] R. Ondo-Ndong, H. Z. Moussambi, H. Gnanga, A. Giani, and A. Foucaran, "Optical properties of ZnO thin films deposed by RF

magnetron," International Journal of Physical Sciences, vol. 10, pp.173-181, Mar. 2015.

- [17] K. S. Kim, H. W. Kim, and N. H. Kim, "Structural characterization of ZnO films grown on SiO<sub>2</sub> by the RF magnetron sputtering," *Physica B: Condensed Matter*, vol. 334, pp. 343-346, Jul. 2003.
- [18] R. S. Sreedharan, V. Ganesan, C. P. Sudarsanakumar, K. Bhavsar, R. Prabhu, and V.P.P.M. Pillai, "Highly textured and transparent RF sputtered Eu<sub>2</sub>O<sub>3</sub> doped ZnO films," *Nano Reviews*, vol. 6, pp. 1-16, Mar. 2015.
- [19] A. K. Kalita and S. Karmakar, "Effect on particle size and microstrain due to iron doping on ZnO nanoparticle prepared by wet chemical method," *International Journal of Scientific Research*, vol. 5, pp. 654-655, Apr. 2016.
- [20] S. Kunj and K. Sreenivas, "Residual stress and defect content in magnetron sputtered ZnO films grown on unheated glass substrates," *Current Applied Physics*, vol. 16, pp. 748-756, Jul. 2016.
- [21] I. M. Yassin, A. Zabidi, M. S. A. M. Ali, N. M. Tahir, H. A. Hassan, H. Z. Abidin, and Z. I. Rizman, "Binary particle swarm optimization structure selection of nonlinear autoregressive moving average with exogenous inputs (NARMAX) model of a flexible robot arm," *International Journal on Advanced Science*, *Engineering and Information Technology*, vol. 6, pp. 630-637, Oct. 2016.
- [22] M. N. M. Nor, R. Jailani, N. M. Tahir, I. M. Yassin, Z. I. Rizman, and R. Hidayat, "EMG signals analysis of BF and RF muscles in autism spectrum disorder (ASD) during walking," *International Journal on Advanced Science, Engineering and Information Technology*, vol. 6, pp. 793-798, Oct. 2016.